

L Number	Hits	Search Text	DB	Time stamp
1	717	(216/2).CCLS.	USPAT; US-PGPUB	2003/09/24 12:51
2	60	((216/2).CCLS.) and (etch\$3 and trench\$2).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:37
3	46	((216/2).CCLS.) and ((etch\$3 adj stop\$3) or (etch-stop)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:07
4	812	(438/22).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:13
5	149	(438/24).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:14
6	453	(438/48).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:14
7	289	(438/50).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:15
8	327	(438/52).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:15
9	738	(438/689).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:16
11	3465	(438/694).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:16
12	374	(438/696).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:16
13	794	(438/702).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:16
14	661	(438/700).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:18
15	484	(438/719).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:18

16	360	(438/734).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:19
17	584	(216/24).CCLS.	USPAT; US-PGPUB	2003/09/24 13:34
18	56	((216/24).CCLS.) and etch\$3 and trench\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:34
19	69	((216/2).CCLS.) and (trench\$2).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:40
20	19	((216/2).CCLS.) and (backside).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:37
22	83	((216/2).CCLS.) and (channel\$1).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:42
23	53	((216/2).CCLS.) and (groove\$1).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:42
25	1896	(conduct\$3 and insulat\$3 and silicon and etch\$3 and (trench\$2 or groove\$1 or channel\$1)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:47
27	912	((conduct\$3 and insulat\$3 and silicon and etch\$3 and (trench\$2 or groove\$1 or channel\$1)).clm.) and sidewall\$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:49
28	100	((conduct\$3 and insulat\$3 and silicon and etch\$3 and (trench\$2 or groove\$1 or channel\$1)).clm.) and backside	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/09/24 13:49
29	11	etch\$3 and trench and microstructure\$1	JPO; DERWENT	2003/09/24 13:58
30	16	etch\$3 and trench and micromechanical	JPO; DERWENT	2003/09/24 13:58
31	1	1999-444471.NRAN.	DERWENT	2003/09/24 14:01
-	319	"electrically isolated electrode"	USPAT; US-PGPUB	2002/08/21 08:19
-	2	((("6256430") or ("6360036"))).PN.	USPAT; US-PGPUB	2002/08/22 09:02
-	423	(etch\$3 near3 backside) and conduct\$3 and insulat\$3	USPAT; US-PGPUB	2002/08/22 09:22
-	51	(etch\$3 near3 backside) and conduct\$3 and insulat\$3 and trench and sidewall	USPAT; US-PGPUB	2002/08/22 10:33
-	101	(etch\$3 near3 backside) and conduct\$3 and insulat\$3 and (trench or channel or groove or via or hole) and sidewall	USPAT; US-PGPUB	2002/08/26 14:59
-	377	(etch\$3 near3 backside) and conduct\$3 and insulat\$3 and (trench or channel or groove or via or hole)	USPAT; US-PGPUB	2002/08/23 10:56
-	197	MEMS and etch\$3 and SOI	USPAT; US-PGPUB	2003/09/24 13:12
-	743	MEMS and etch\$3 and conduct\$3 and insulat\$3 and (trench or groove or via or hole or channel)	USPAT; US-PGPUB	2002/08/26 14:57

-	3709	isolated near3 (electrode or conduct\$3) and etch\$3	USPAT; US-PGPUB	2002/08/23 12:33
-	475	(216/18).CCLS.	USPAT; US-PGPUB	2003/09/24 12:51
-	62	(216/19).CCLS.	USPAT; US-PGPUB	2002/08/23 12:34
-	454	(216/24).CCLS.	USPAT; US-PGPUB	2003/09/24 13:33
-	229	(216/39).CCLS.	USPAT; US-PGPUB	2002/08/23 12:37
-	71	(216/46).CCLS.	USPAT; US-PGPUB	2002/08/23 12:40
-	555	(216/79).CCLS.	USPAT; US-PGPUB	2002/08/23 12:40
-	628	(216/99).CCLS.	USPAT; US-PGPUB	2002/08/23 12:41
-	775	MEMS and etch\$3 and conduct\$3 and insulat\$3 and (trench or cavity or groove or via or hole or channel)	USPAT; US-PGPUB	2002/08/23 14:51
-	1	("5980762").PN.	USPAT; US-PGPUB	2002/08/26 09:46
-	8	(silicon adj "110")same trench and etch	USPAT; US-PGPUB	2002/08/26 09:53
-	6229	etch\$3 and conduct\$3 and insulat\$3 and (trench or channel or groove or via or hole or cavity)	JPO; DERWENT	2002/08/26 15:08
-	1	etch\$3 and conduct\$3 and insulat\$3 and (trench or channel or groove or via or hole or cavity)and MEMS	JPO; DERWENT	2002/08/26 15:03
-	598	etch\$3 and conduct\$3 and insulat\$3 and trench	JPO; DERWENT	2002/08/27 10:43
-	12	etch\$3 and trench and (microelectromechanical or MEMS)	JPO; DERWENT	2003/09/24 13:57
-	1	("6121552").PN.	USPAT; US-PGPUB	2002/08/27 10:52
-	3	((("6416831") or ("5017947") or ("4233109"))).PN.	USPAT; US-PGPUB	2003/04/29 16:49

Inventor Name Search Result

Your Search was:

Last Name = DANEMAN

First Name = MICHAEL

Application#	Patent#	Status	Date Filed	Title	Inventor Name
60357160	Not Issued	159	02/12/2002	FAST MEMS OPTICAL SWITCH ACTUATION USING PRE-BIAS FORCE AND ROTATING MAGNETIC FIELD	DANEMAN, MICHAEL J
60303755	Not Issued	159	07/07/2001	COMPACT MAGNET ASSEMBLY FOR MEMS DEVICE	DANEMAN, MICHAEL J
60250237	Not Issued	159	11/29/2000	MEMS PACKAGE WITH OPTICAL WINDOWS	DANEMAN, MICHAEL J
60250081	Not Issued	159	11/29/2000	SINGLE-WAFER PROCESS TO BUILD MEMS ROTATING MIRRORS WITH PRECISION CLAMPING MECHANISM	DANEMAN, MICHAEL J
60196055	Not Issued	159	04/10/2000	CAPACITIVE SENSING SCHEME FOR MIRROR POSITION DETECTION IN OPTICAL SWITCHES	DANEMAN, MICHAEL J
60192144	Not Issued	159	03/24/2000	METHOD FOR CONTROLLED RELEASE USING ETCH-STOP TRENCHES	DANEMAN, MICHAEL J
60191987	Not Issued	159	03/24/2000	TWO-DIMENSIONAL GIMBALED SCANNING ACTUATOR WITH VERTICAL ELECTROSTATIC COMB-DRIVE FOR ACTUATION AND/OR SENSING	DANEMAN, MICHAEL
10469516	Not Issued	019	01/01/0001	OPTICATL CROSS-CONNECT SYSTEM	DANEMAN, MICHAEL
10003054	Not Issued	120	12/06/2001	HIGH CONTRAST GRATING LIGHT VALVE	DANEMAN, MICHAEL J
09989905	Not Issued	041	11/20/2001	ENCLOSURE FOR MEMS APPARATUS AND METHOD OF USING THE SAME	DANEMAN, MICHAEL J
09949210	Not Issued	041	09/07/2001	TILING OF OPTICAL MEMS DEVICES	DANEMAN, MICHAEL J
09932433	Not Issued	041	08/18/2001	USE OF APPLIED FORCE TO IMPROVE MEMS SWITCH PERFORMANCE	DANEMAN, MICHAEL J
09917490	6480319	150	07/28/2001	APPARATUS AND METHOD FOR 2-	DANEMAN, MICHAEL J

				DIMENSIONAL STEERED-BEAM NXM OPTICAL SWITCH USING SINGLE-AXIS MIRROR ARRAYS	
<u>09917431</u>	<u>6437902</u>	150	07/28/2001	OPTICAL BEAM STEERING SWITCHING SYSTEM	DANEMAN, MICHAEL J
<u>09912150</u>	Not Issued	093	07/23/2001	MECHANICAL LANDING PAD FORMED ON THE UNDERSIDE OF A MEMS DEVICE	DANEMAN, MICHAEL J
<u>09900841</u>	<u>6514781</u>	150	07/07/2001	MAINTAINING THE STATE OF A MEMS DEVICE IN THE EVENT OF A POWER FAILURE	DANEMAN, MICHAEL J
<u>09835115</u>	Not Issued	071	04/13/2001	PROCESS FOR CREATING AN ELECTRICALLY ISOLATED ELECTRODE ON A SIDEWALL OF A CAVITY IN A BASE	DANEMAN, MICHAEL J
<u>09834744</u>	Not Issued	071	04/12/2001	MEMS MIRRORS WITH PRECISION CLAMPING MECHANISM	DANEMAN, MICHAEL J
<u>09812066</u>	Not Issued	071	03/17/2001	THREE DIMENSIONAL OPTICAL SWITCHES AND BEAM STEERING MODULES	DANEMAN, MICHAEL J
<u>09802619</u>	Not Issued	071	03/08/2001	HIGH CONTRAST GRATING LIGHT VALVE	DANEMAN, MICHAEL J
<u>09798129</u>	<u>6528887</u>	150	03/01/2001	CONDUCTIVE EQUIPOTENTIAL LANDING PADS FORMED ON THE UNDERSIDE OF A MEMS DEVICE	DANEMAN, MICHAEL J
<u>09751660</u>	Not Issued	071	12/28/2000	TWO-DIMENSIONAL GIMBALED SCANNING ACTUATOR WITH VERTICAL ELECTROSTATIC COMB- DRIVE FOR ACTUATION AND/OR SENSING	DANEMAN, MICHAEL J
<u>09724948</u>	Not Issued	041	11/28/2000	CAPACITIVE SENSING SCHEME FOR DIGITAL CONTROL STATE DETECTION IN OPTICAL SWITCHES	DANEMAN, MICHAEL J
<u>09712420</u>	Not Issued	041	11/13/2000	FABRICATION AND CONTROLLED RELEASE OF STRUCTURES USING ETCH-STOP TRENCHES	DANEMAN, MICHAEL J
<u>09546432</u>	<u>6586841</u>	150	04/10/2000	MECHANICAL LANDING PAD FORMED ON THE UNDERSIDE OF A MEMS DEVICE	DANEMAN, MICHAEL
<u>09536164</u>	<u>6330102</u>	150	03/25/2000	APPARATUS AND METHOD FOR 2- DIMENSIONAL STEERED-BEAM NXM OPTICAL SWITCH USING SINGLE-AXIS MIRROR ARRAYS AND RELAY OPTICS	DANEMAN, MICHAEL J
<u>09518754</u>	<u>6473544</u>	150	03/03/2000	OPTICAL SWITCH HAVING EQUALIZED BEAM SPREADING IN ALL CONNECTIONS	DANEMAN, MICHAEL
<u>09518751</u>	<u>6449407</u>	150	03/03/2000	OPTICAL SWITCHING HAVING	DANEMAN, MICHAEL

				EQUALIZED BEAM SPREADING IN ALL CONNECTIONS	
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Inventor Search Completed: No Records to Display.

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	DANEMAN	MICHAEL	

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Inventor Name Search Result

Your Search was:

Last Name = LIN

First Name = CHUANG-CHIA

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<u>10193804</u>	Not Issued	094	07/11/2002	MICROMECHANICAL AND MICROOPTOMECHANICAL STRUCTURES WITH SINGLE CRYSTAL SILICON EXPOSURE STEP	LIN, CHUANG-CHIA
<u>10192087</u>	Not Issued	040	07/09/2002	MICROMECHANICAL AND MICROOPTOMECHANICAL STRUCTURES WITH BACKSIDE METALIZATION	LIN, CHUANG-CHIA
<u>10040687</u>	Not Issued	041	01/07/2002	SELF-ALIGNED MICRO HINGES	LIN, CHUANG-CHIA
<u>09915232</u>	Not Issued	030	07/24/2001	MEMS ELEMENT HAVING PERPENDICULAR PORTION FORMED FROM SUBSTRATE	LIN, CHUANG-CHIA
<u>09915217</u>	<u>6583031</u>	150	07/25/2001	METHOD OF MAKING A MEMS ELEMENT HAVING PERPENDICULAR PORTION FORMED FROM SUBSTRATE	LIN, CHUANG-CHIA
<u>09891760</u>	Not Issued	041	06/25/2001	SELF ASSEMBLED MICRO ANTI-STICTION STRUCTURE	LIN, CHUANG-CHIA
<u>09858469</u>	<u>6413793</u>	150	05/17/2001	METHOD OF FORMING PROTRUSIONS ON SINGLE CRYSTAL SILICON STRUCTURES BUILT ON SILICON-ON-INSULATOR WAFERS	LIN, CHUANG-CHIA
<u>09835115</u>	Not Issued	071	04/13/2001	PROCESS FOR CREATING AN ELECTRICALLY ISOLATED ELECTRODE ON A SIDEWALL OF A CAVITY IN A BASE	LIN, CHUANG-CHIA
<u>09834744</u>	Not Issued	071	04/12/2001	MEMS MIRRORS WITH PRECISION CLAMPING MECHANISM	LIN, CHUANG-CHIA
<u>09724515</u>	<u>6506620</u>	150	11/27/2000	PROCESS FOR MANUFACTURING MICROMECHANICAL AND MICROOPTOMECHANICAL STRUCTURES WITH BACKSIDE METALIZATION	LIN, CHUANG-CHIA
<u>09724514</u>	<u>6479315</u>	150	11/27/2000	PROCESS FOR MANUFACTURING MICROMECHANICAL AND MICROOPTOMECHANICAL	LIN, CHUANG-CHIA

				STRUCTURES WITH SINGLE CRYSTAL SILICON EXPOSURE STEP	
<u>09724506</u>	<u>6479311</u>	150	11/27/2000	PROCESS FOR MANUFACTURING MICROMECHANICAL AND MICROOPTOMECHANICAL STRUCTURES WITH PRE-APPLIED PATTERNING	LIN, CHUANG-CHIA
<u>09718017</u>	Not Issued	071	11/20/2000	SILICON ON INSULATOR AND POLYSILICON WAFER FABRICATION PROCESS FOR MEMS	LIN, CHUANG-CHIA

Inventor Search Completed: No Records to Display.

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Inventor Name Search Result

Your Search was:

Last Name = KOBRIN

First Name = BORIS

Application#	Patent#	Status	Date Filed	Title	Inventor Name
60485082	Not Issued	020	07/07/2003	APPARATUS & PROCESS FOR VAPOR PHASE DEPOSITION	KOBRIN, BORIS
60479883	Not Issued	020	06/20/2003	DRY PROCESSING TOOL FOR STICTION-FREE MEMS RELEASE	KOBRIN, BORIS
60470971	Not Issued	020	05/16/2003	METHOD OF CONTROLLED OXIDE ETCH	KOBRIN, BORIS
60454700	Not Issued	020	03/17/2003	PROCESS ACTUATION OF MEMS MOVABLE STRUCTURES	KOBRIN, BORIS
60454543	Not Issued	020	03/17/2003	METHOD OF SURFACE MODIFICATION FOR MENS RELEASE AND PASSIVATION	KOBRIN, BORIS
60318099	Not Issued	159	09/07/2001	MEMS OPTICAL SWITCH WITH MOVABLE DIFFRACTION GRATINGS	KOBRIN, BORIS
60255734	Not Issued	159	12/14/2000	MEMS OPTICAL SWITCH WITH PNEUMATIC ACTUATION	KOBRIN, BORIS
60255733	Not Issued	159	12/14/2000	MEMS OPTICAL SWITCH WITH ACOUSTIC PULSE ACTUATION	KOBRIN, BORIS
60250081	Not Issued	159	11/29/2000	SINGLE-WAFER PROCESS TO BUILD MEMS ROTATING MIRRORS WITH PRECISION CLAMPING MECHANISM	KOBRIN, BORIS
60162197	Not Issued	159	10/29/1999	MAGNETIC POLE FABRICATION PROCESS AND DEVICE	KOBRIN , BORIS
60153074	Not Issued	159	09/10/1999	MAGNETIC POLE FABRICATION PROCESS AND DEVICE	KOBRIN , BORIS
60061860	Not Issued	159	10/15/1997	LINEAR, ROTATIONAL AND CONFORNAL ENCODERS, BASED ON FIBER GRATINGS, FOR RELATIVE OR ABSOLUTE MOVEMENT DETECTION, AND METHODS FOR FABRICATION THE SAME	KOBRIN , BORIS
09992531	Not Issued	041	11/06/2001	MEMS OPTICAL SWITCH WITH PNEUMATIC ACTUATION	KOBRIN, BORIS
09992530	Not Issued	041	11/06/2001	MEMS OPTICAL SWITCH WITH ACOUSTIC PULSE ACTUATION	KOBRIN, BORIS

09835115	Not Issued	071	04/13/2001	PROCESS FOR CREATING AN ELECTRICALLY ISOLATED ELECTRODE ON A SIDEWALL OF A CAVITY IN A BASE	KOBRIN, BORIS
09834744	Not Issued	071	04/12/2001	MEMS MIRRORS WITH PRECISION CLAMPING MECHANISM	KOBRIN, BORIS
09789250	Not Issued	161	02/20/2001	TWO-SIDED MEMS DEVICE AND OPTICAL SWITCH	KOBRIN, BORIS
09696739	6547975	150	10/26/2000	MAGNETIC POLE FABRICATION PROCESS AND DEVICE	KOBRIN, BORIS
09658023	6540928	150	09/08/2000	MAGNETIC POLE FABRICATION PROCESS AND DEVICE	KOBRIN, BORIS
09081286	6087655	150	05/19/1998	FIBER GRATING ENCODERS AND METHODS FOR FABRICATING THE SAME	KOBRIN , BORIS

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